



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

00862.022434.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Shinichi SHIMA) Examiner: H. Nguyen
Application No.: 09/986,958) Group Art Unit: 2851
Filed: November 13, 2001) Confirmation No.: 638
For: EXPOSURE APPARATUS, METHOD OF)
MANUFACTURING SEMICONDUCTOR)
DEVICES, SEMICONDUCTOR MANUFACTURING)
PLANT, METHOD OF MAINTAINING EXPOSURE)
APPARATUS, AND POSITION DETECTOR)

RECEIVED
OCT 15 2003
TECHNOLOGY CENTER 2806

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION AND LETTER
FORWARDING SUBSTITUTE SPECIFICATION

Sir:

In response to the Official Action dated July 11, 2003, please amend the above-identified application as follows:

Do not
enter
10/21/03
HN